



IFW

Docket No. 0524-0139.01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:)
)
Nozawa et al.)
)
Serial No.: 10/771,997)
)
Filed: February 4, 2004)
)
For: Manufacturing Method And Apparatus of)
Phase Mask Shift Blank)
)
Examiner: Steven Versteeg)
)
)
Art Unit: 1753)

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:
Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450 on

December 23, 2005
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Shannon Wallace

Name of applicant, assignee, or Registered Rep.
Shannon Wallace 12/23/05
Signature Date

AMENDMENT D

Commissioner of Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action of August 25, 2005, a one month extension of time having already been submitted, please amend the above-identified application as follows: